

# Hyug-Gyo Rhee

## List of Publications by Year in descending order

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Version: 2024-02-01

16  
papers

175  
citations

1307594

7  
h-index

1125743

13  
g-index

17  
all docs

17  
docs citations

17  
times ranked

119  
citing authors

#	ARTICLE	IF	CITATIONS
1	Realization and performance evaluation of high speed autofocusing for direct laser lithography. Review of Scientific Instruments, 2009, 80, 073103.	1.3	42
2	Single-shot deflectometry for dynamic 3D surface profile measurement by modified spatial-carrier frequency phase-shifting method. Scientific Reports, 2019, 9, 3157.	3.3	24
3	Improvement of linewidth in laser beam lithographed computer generated hologram. Optics Express, 2010, 18, 1734.	3.4	19
4	Simultaneous measurements of top surface and its underlying film surfaces in multilayer film structure. Scientific Reports, 2017, 7, 11843.	3.3	19
5	Absolute three-dimensional coordinate measurement by the two-point diffraction interferometry. Optics Express, 2007, 15, 4435.	3.4	18
6	Modeling of edge tool influence functions for computer controlled optical surfacing process. International Journal of Advanced Manufacturing Technology, 2016, 83, 911-917.	3.0	11
7	Improved wavefront reconstruction algorithm from slope measurements. Journal of the Korean Physical Society, 2017, 70, 469-474.	0.7	9
8	300 mm reference wafer fabrication by using direct laser lithography. Review of Scientific Instruments, 2008, 79, 103103.	1.3	8
9	Pixel-based absolute test of a 1-m lightweight mirror for a space telescope. Journal of the Korean Physical Society, 2014, 65, 1385-1389.	0.7	7
10	Dual-line fabrication method in direct laser lithography to reduce the manufacturing time of diffractive optics elements. Optics Express, 2017, 25, 1636.	3.4	7
11	Performance evaluation of laser lithographic machine for computer-generated hologram. International Journal of Advanced Manufacturing Technology, 2011, 52, 1005-1009.	3.0	3
12	Enhancement of height resolution in direct laser lithography. Optics Express, 2012, 20, 291.	3.4	3
13	Stress-relieved assembly method for a high-resolution airborne optical system. Journal of the Korean Physical Society, 2012, 60, 1032-1036.	0.7	2
14	Denosing phase unwrapping algorithm for precise phase shifting interferometry. Journal of the Korean Physical Society, 2017, 71, 82-87.	0.7	2
15	Dual-path Phase Unwrapping Algorithm Based on Geodesic Curvature for Interferometric Fringe Analysis. Journal of the Korean Physical Society, 2020, 76, 202-209.	0.7	1
16	Fabrication of Dual-Line by Using a Laser Ablation Phenomenon in Direct Laser Lithographic System. Journal of the Korean Society for Precision Engineering, 2019, 36, 1003-1007.	0.2	0